

Attorney Docket: 061063-0318214
Client Reference: OSP-18831

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of
NAKADA ET AL.

Confirmation Number: 5511

Application No.: 10/551,695

Group Art Unit: 1792

Filed: September 30, 2005

Examiner: AHMED, SHAMIM

Title: HEAT TREATMENT JIG AND HEAT TREATMENT METHOD FOR SILICON WAFER

COMMENTS ON EXAMINER'S STATEMENT OF REASONS FOR ALLOWANCE

Mail Stop Issue Fee
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the Notice of Allowability dated September 22, 2008, consideration of the following comments are respectfully requested.

In the Notice of Allowability, the Examiner has set forth "Reasons for Allowance." The Applicant respectfully traverses these Reasons. Specifically, it is submitted that the subject matter of the allowed claims are patentable for their respective recitations of claimed combinations as a whole, without any particular criticality or distinguishing feature being attributable to any one or more of such features, and without any narrowing interpretation being imposed on any of such features. The Applicant respectfully submits that the dependent claims are allowable not only for their dependence on the allowed independent claims, but also for the additional subject matter recited in each of those dependent claims.

Respectfully submitted,

PILLSBURY WINTHROP SHAW PITTMAN LLP

E. Rico Hernandez 39328
S/ E. Rico Hernandez
Reg. No. 47641
Tel. No. (703) 770-7788
Fax No. (703) 770-7901

Date: December 19, 2008

P.O. Box 10500
McLean, VA 22102
(703) 770-7900